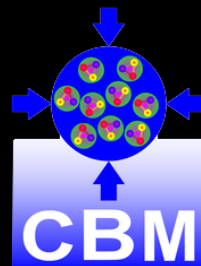


The MVD of the CBM experiment at FAIR: Selected Aspects of Mechanical Integration.

Michal Koziel
University of Frankfurt

koziel@physik.uni-frankfurt.de



Outline:



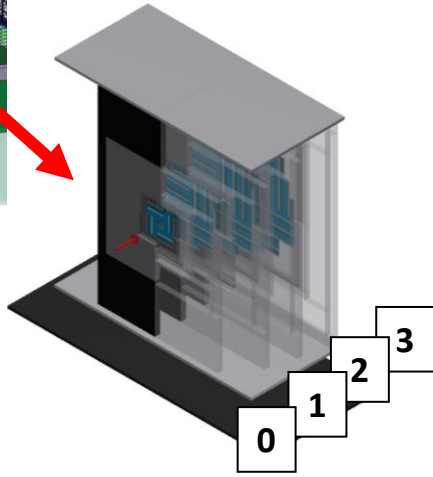
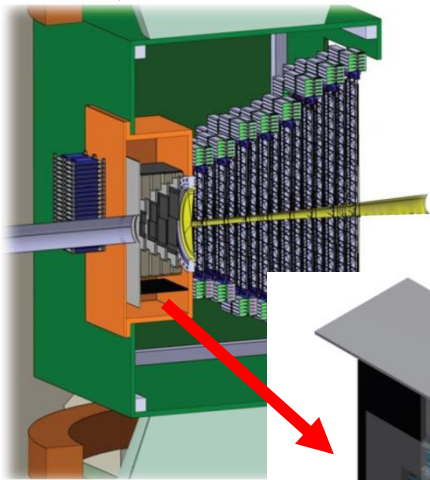
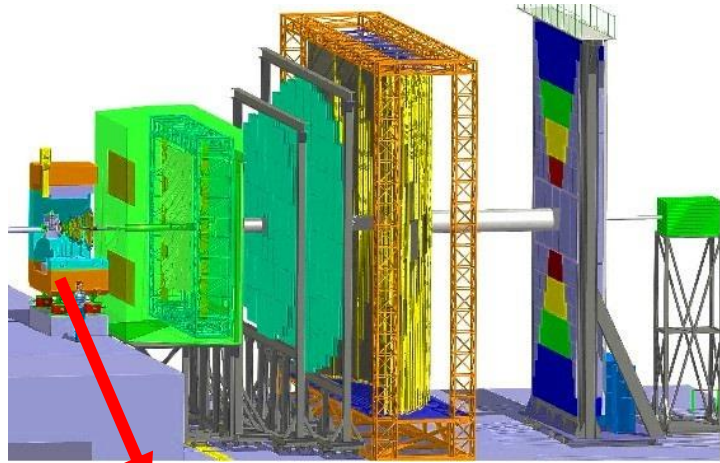
- The Micro Vertex Detector for the CBM experiment: requirements
- Material budget
- R&D towards CBM-MVD and synergies with other experiments
 - Vacuum compatibility
 - Adhesives
 - Commissioning of ultra thin Si sensors
- Support materials
 - Thermal simulations
 - laboratory tests in preparation
- Outlook

The MVD – required performance



CBM-MVD will:

- improve secondary vertex resolution
- host highly granular silicon pixel sensors featuring fast read-out, excellent spatial resolution and robustness to radiation environment.



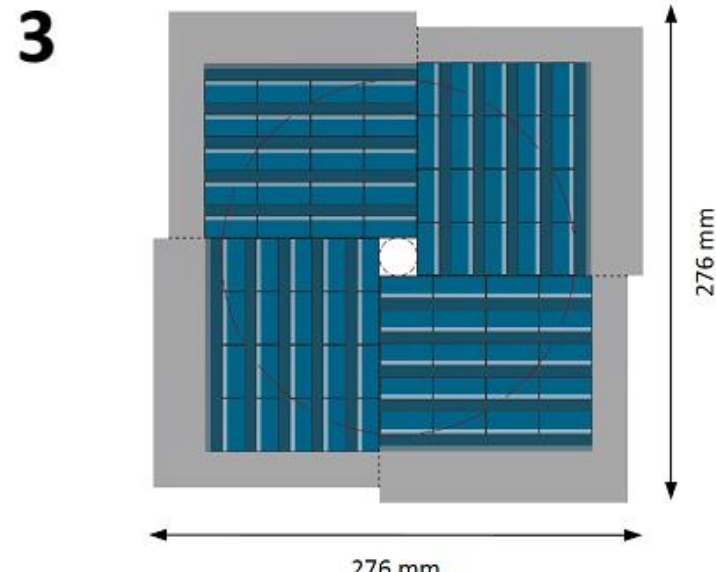
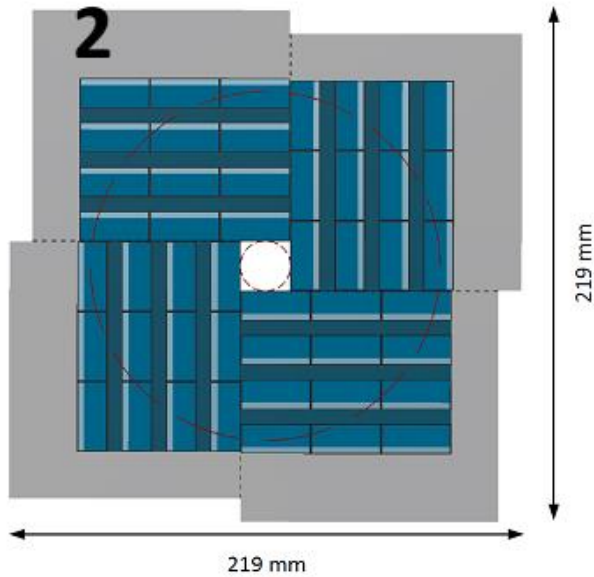
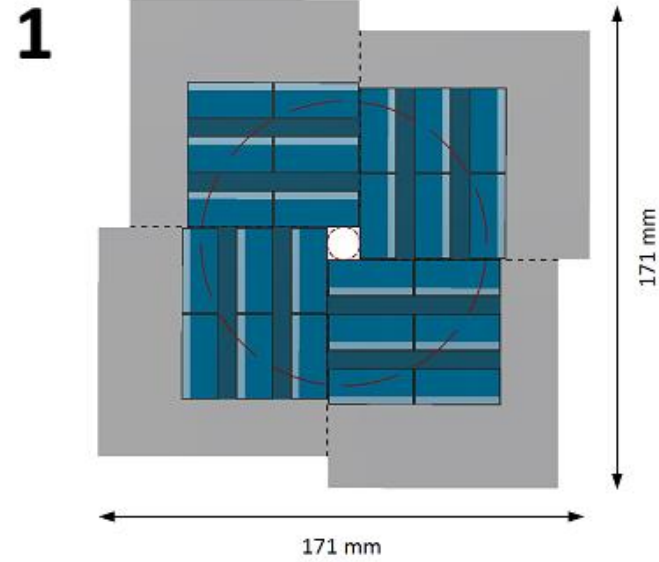
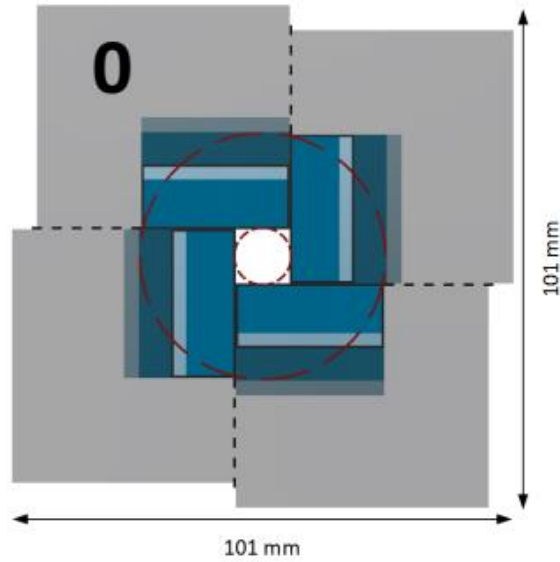
Required performances (SIS-100)

Radiation tolerance	$> 10^{13} n_{eq}/cm^2$ & > 3 MRad
Read-out speed	> 30 kframes/s \Rightarrow 500 Gbit/s/MVD, Free streaming
Intrinsic resolution	$< 5 \mu m$
Operation in vacuum and magnetic field	
„Light” support and cooling	Material budget (station 0) of $\sim 0.3 \% x/X_0$

The MVD – stations



Stations 0 – 3, front view





Material budget

Assumptions:

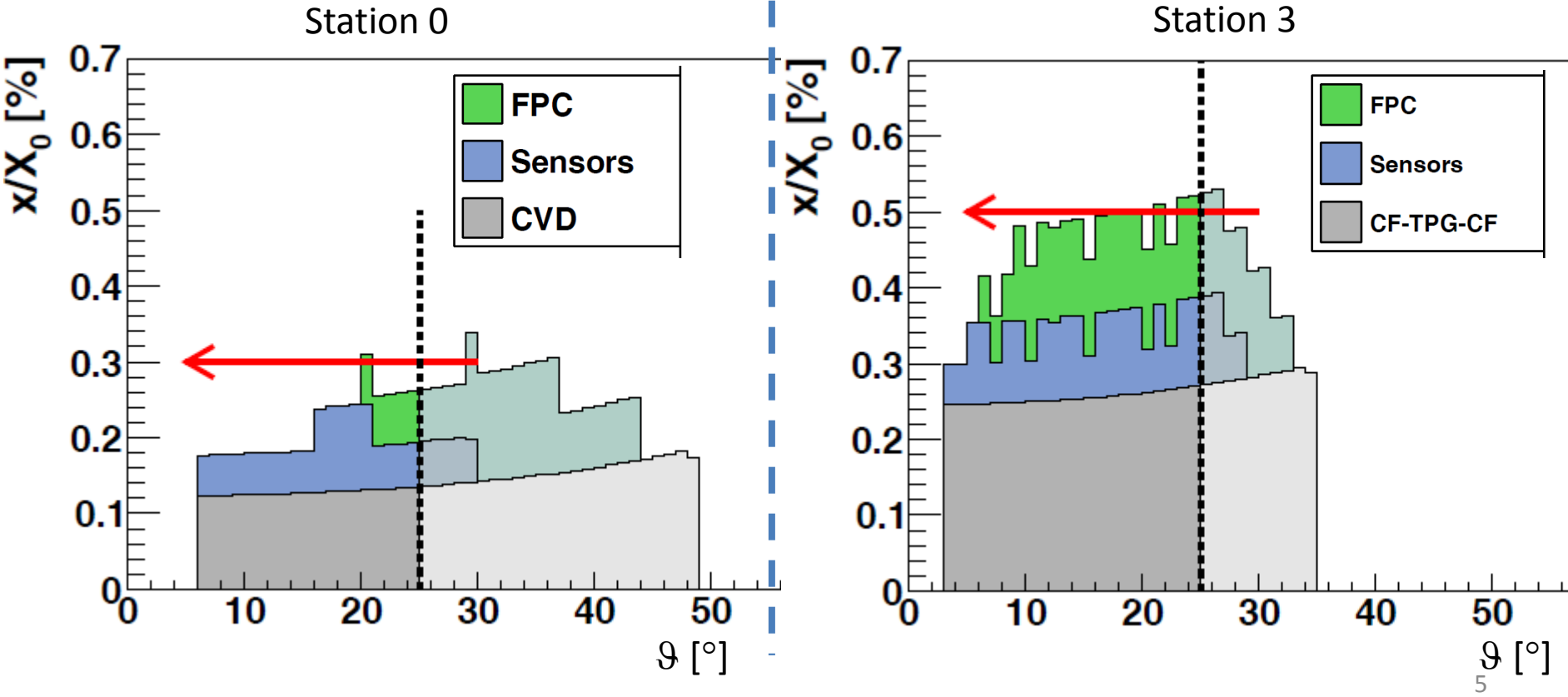
Carrier: CVD diamond (150 μm)/ CF-TPG-CF (500 μm) (do we need CF reinforcement ?)

Sensors: 50 μm Si

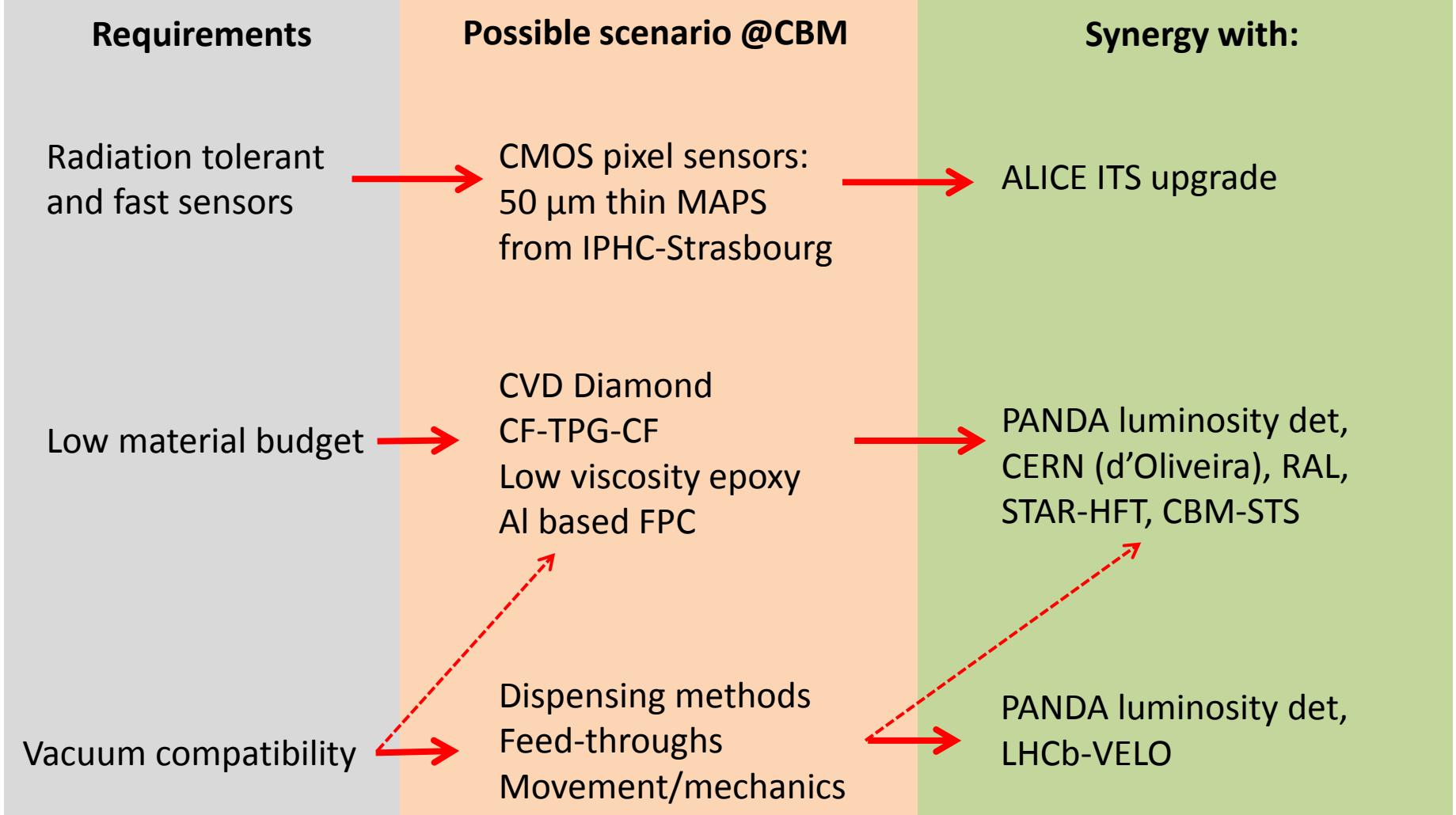
FPC: Cu traces , 1 layer, 1 cable / 2 sensors, material budget of 0.06% x/X_0

No encapsulation for wire bonds yet

Glue: 10-30 μm epoxy-based (not shown in the figures)

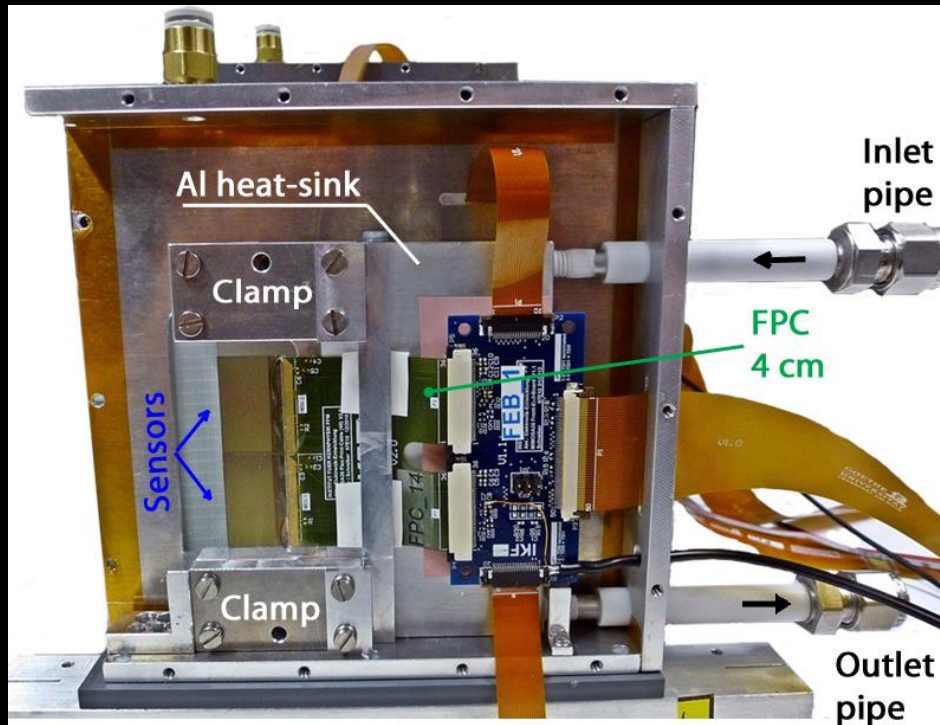


CBM-MVD requirements and synergies





Vacuum compatibility



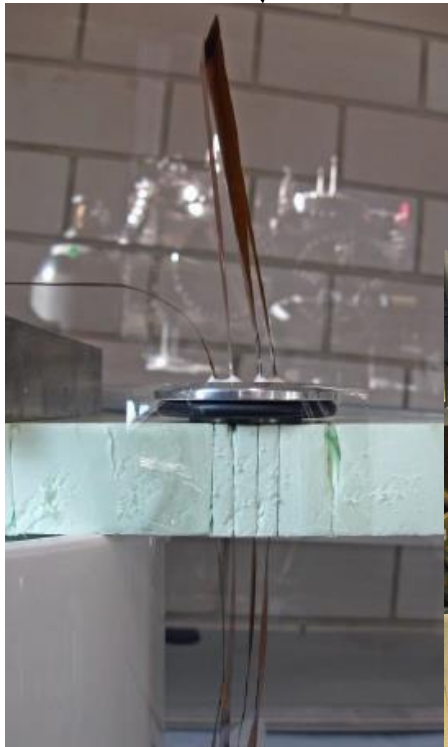
of the CBM-MVD
prototype
addressed with
telescope station.

Vacuum tests: feed-through

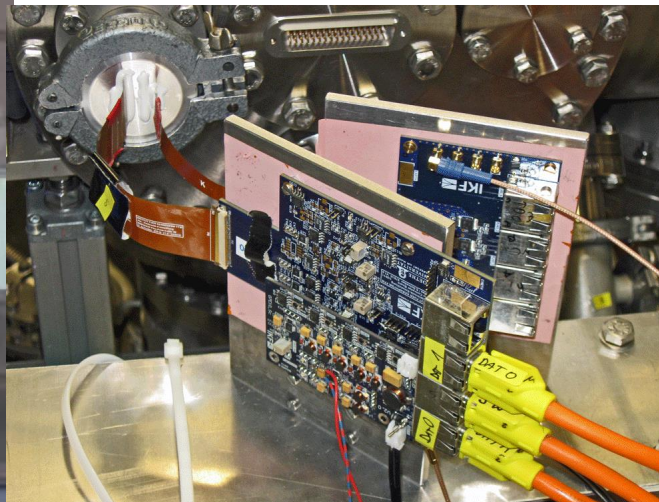


Scenarios:

- easy plug/unplug devices -> dedicated feed-throughs with connectors (FPC)
- minimize no. connections



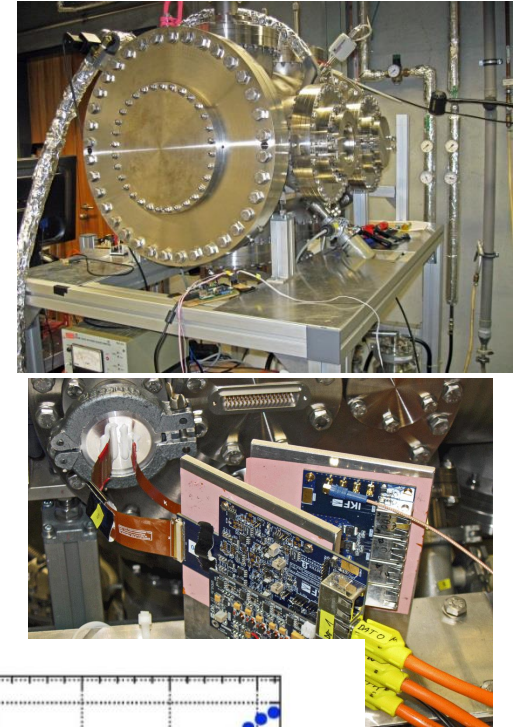
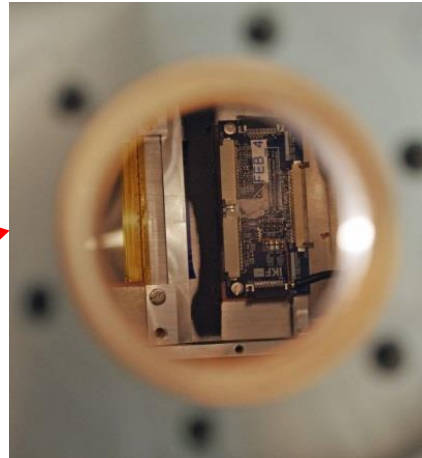
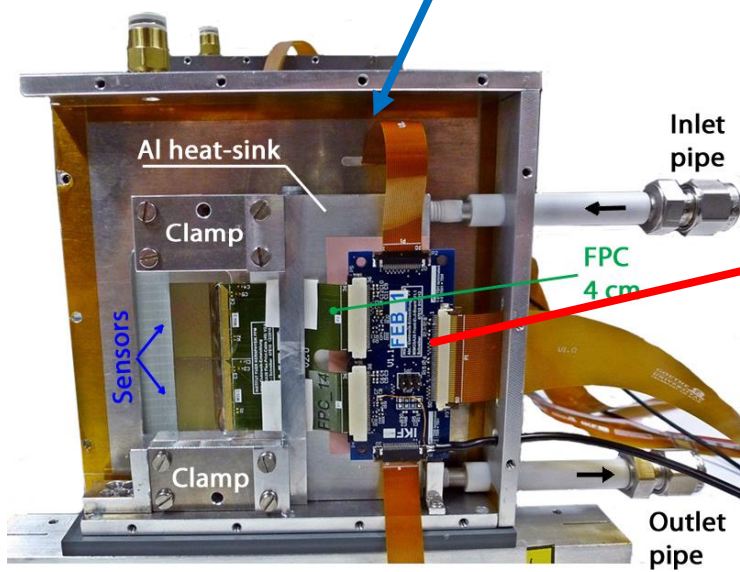
Done at IKF



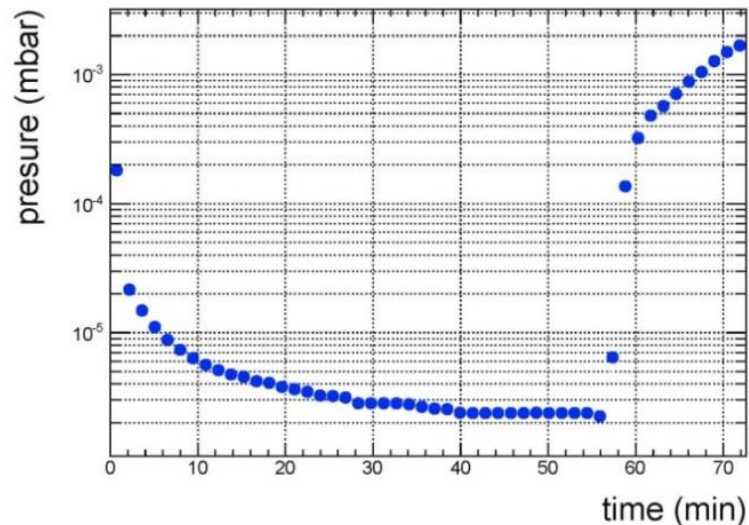
Any experience with making high-density vacuum feed-throughs for differential signals + power supply ?

Vacuum test: Telescope station

[M. Koziel et al., Nucl.Instrum.Meth. A732 \(2013\) pp.515-518](#)

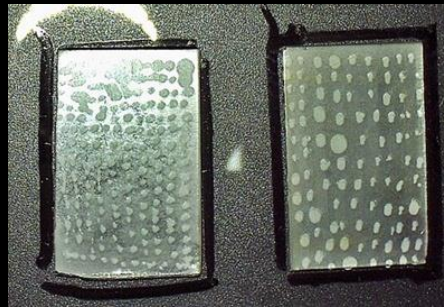


- Single-sided module employing two 50 μm thin MIMOSA-26 sensors integrated onto a 200 μm thin CVD Diamond support
- Liquid cooling for sensors: +15 $^{\circ}\text{C}$
- Operated for several days in vacuum
- Out-gassing studies
- Pressure $2 \cdot 10^{-6}$ mbar reached (same as without module)





Glue

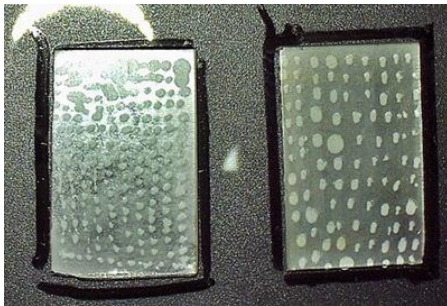


Glue choice



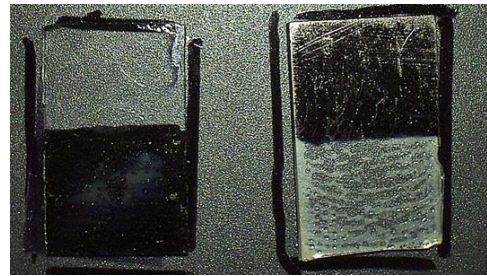
Glue requirements	Epoxy based	Silicone based
Radiation tolerant	Yes	Limited
Easy to rework	No*	Yes
Low material budget	Thin layer easy	Thicker layer
Strong	Yes	Medium
Low outgassing	Yes	No
Soft at -20 °C	No*	Yes
High thermal conductivity*	No	No

Thor Labs S-10



High viscosity

Epotecny E505



Medium viscosity

Epotecny E501



Low viscosity

Used for MVD prototype

Custom-made glue from RAL



Glue requirements	RAL 247
Radiation tolerant	Studies ongoing
Easy to rework	Yes
Low material budget	Yes
Strong enough	Studies ongoing
Low outgassing	Yes
Soft at -20 °C	Yes
High thermal conductivity*	No

*Development at the Rutherford Appleton Laboratory (RAL)
Synergy with the ATLAS experiment*

Irradiation @  Karlsruhe Institute of Technology 

 Science & Technology Facilities Council
Rutherford Appleton Laboratory

More on Wednesday 9:45 by Simon Canfer
„Studies of Adhesives for HL-LHC Tracking Detectors”





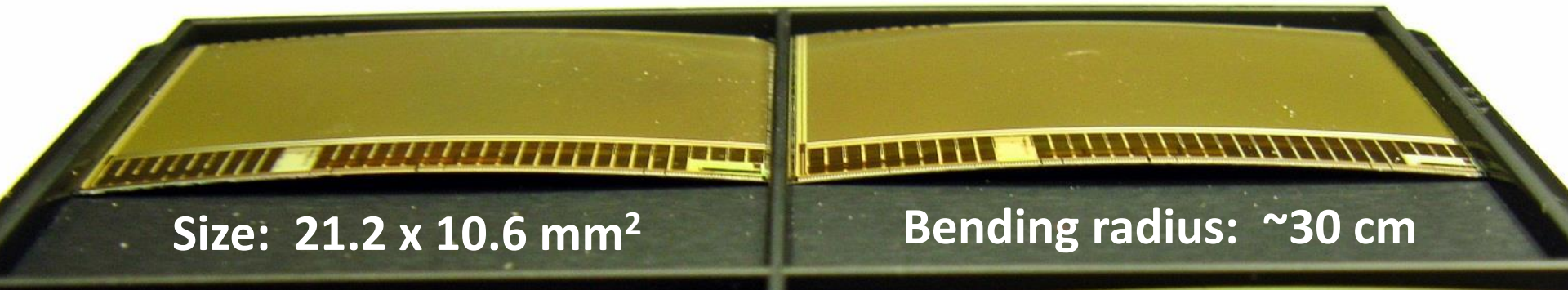
Sensor commissioning



Probe card test of ultra-thin sensors



Precursor of CBM-MVD sensor (used in the MVD prototype)
MIMOSA-26 CMOS sensor
Thickness: $\sim 50 \mu\text{m}$



Size: $21.2 \times 10.6 \text{ mm}^2$

Bending radius: $\sim 30 \text{ cm}$

Future CBM-MVD sensor:
Thickness: $\sim 50 \mu\text{m}$
Size $30 \times 10 \text{ mm}^2$

Mass production



- Quality control before assembly
- Probe tests

...but HOW ?!

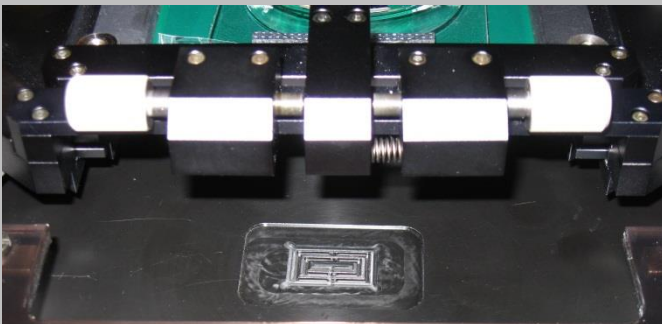
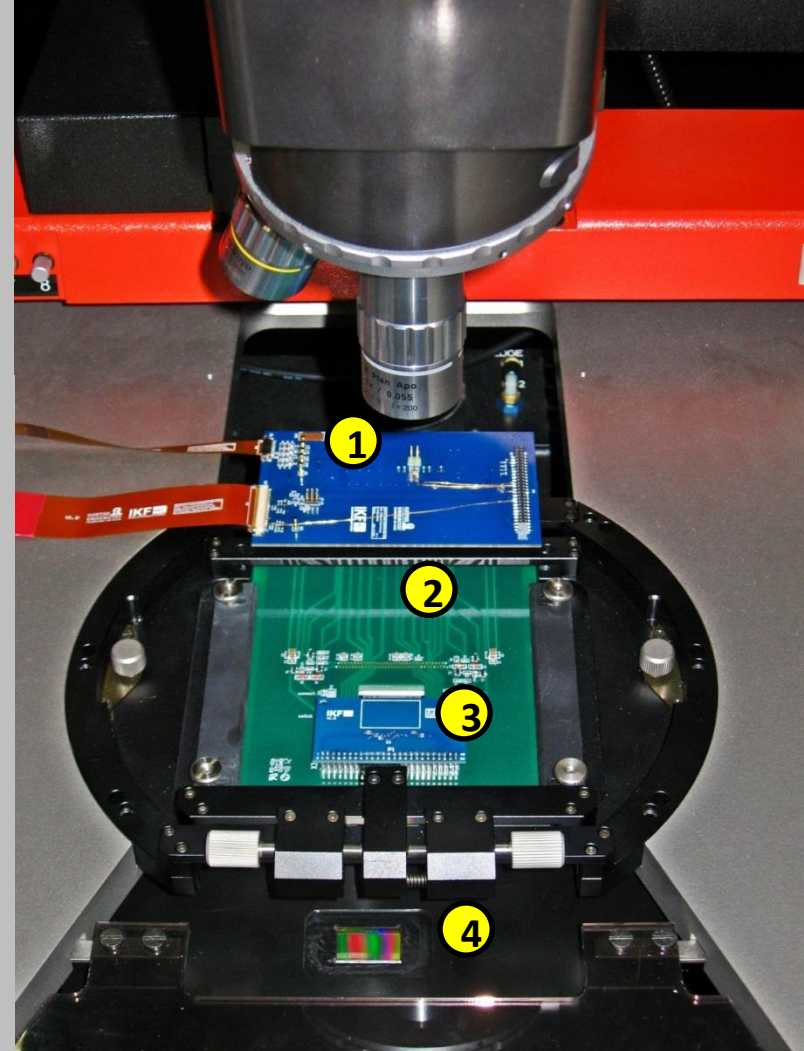
Probe card test of ultra-thin sensors



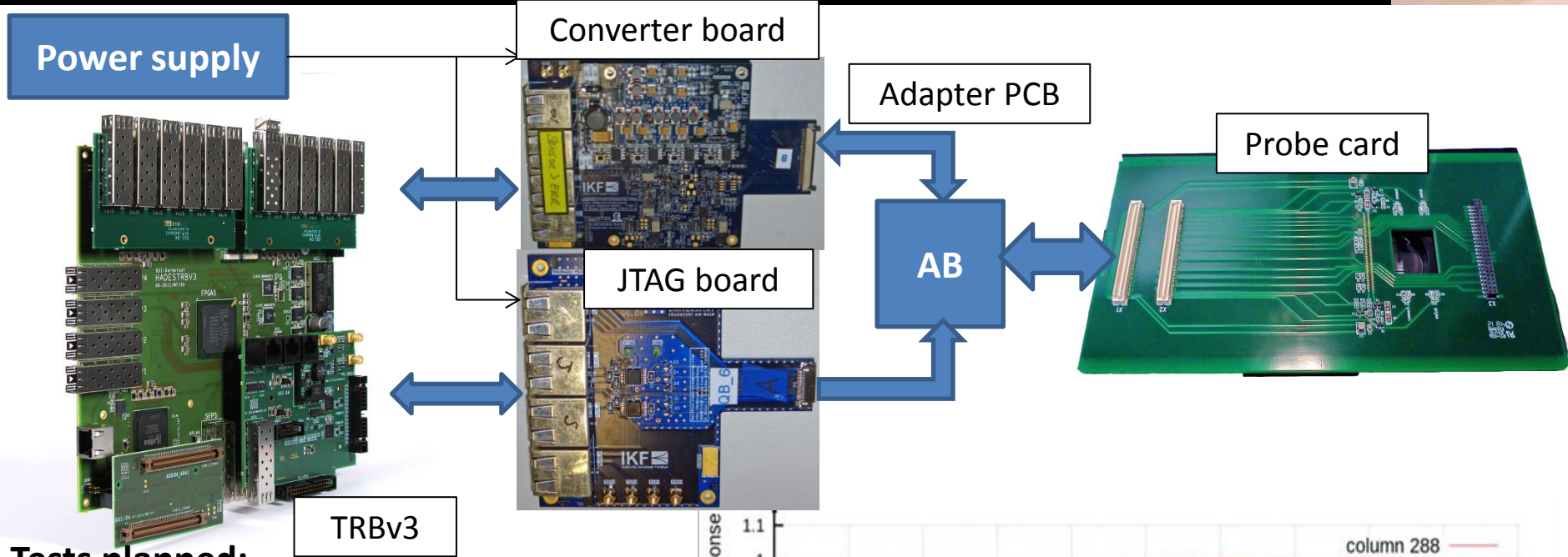
- Located in a dedicate cleanroom (ISO-6) at IKF.
- Suss MicroTec PA-200 probe station is employed.
- Probe station is located inside a light and electromagnetic tight box.



1. Adapter board
2. Probe card head, HTT-Dresden (65 tungsten needles, minimum pitch of 100 μm)
3. Test board
4. Chuck adapter with multi-channel underpressure holding

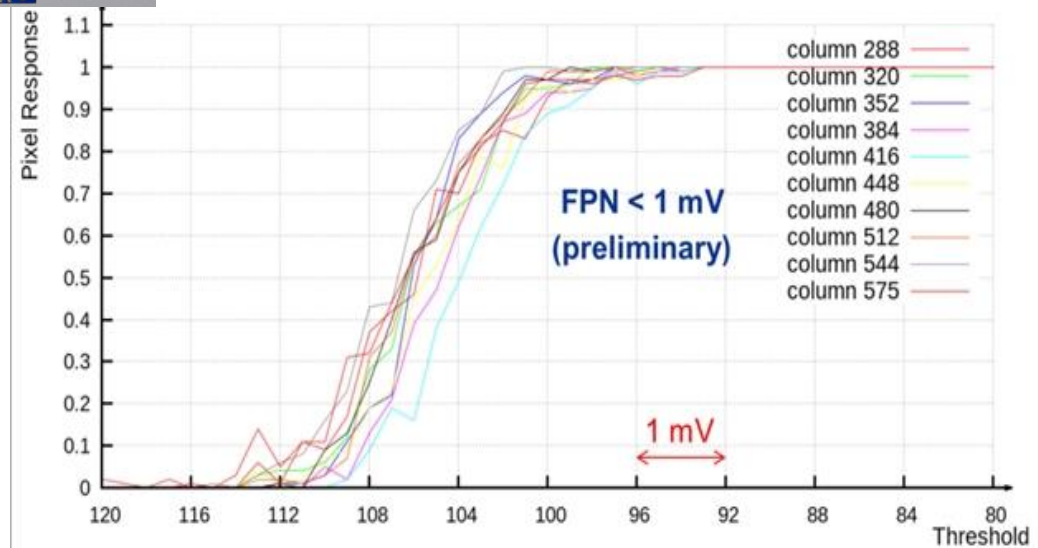


Probe card test of ultra-thin sensors



Tests planned:

- „Smoke test”
- Sensor behaviour and response to JTAG signal
- Check of programming registers
- Dead pixels (tests with pulsing light or radioactive source)
- Hot pixels
- S-curves (noise information)

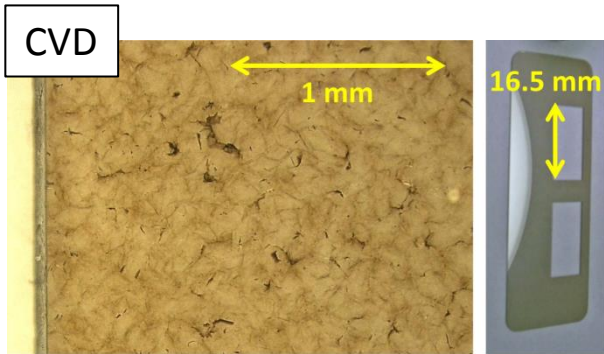
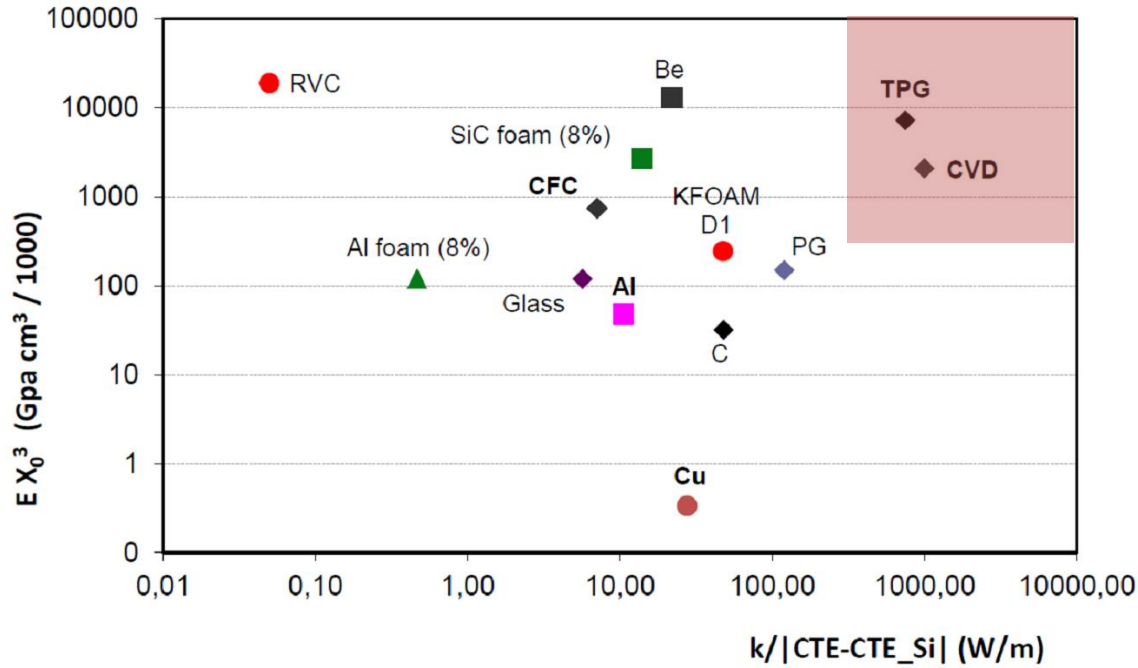


Probe tests of 50 μm thin CMOS sensors can be done with standard probe cards !

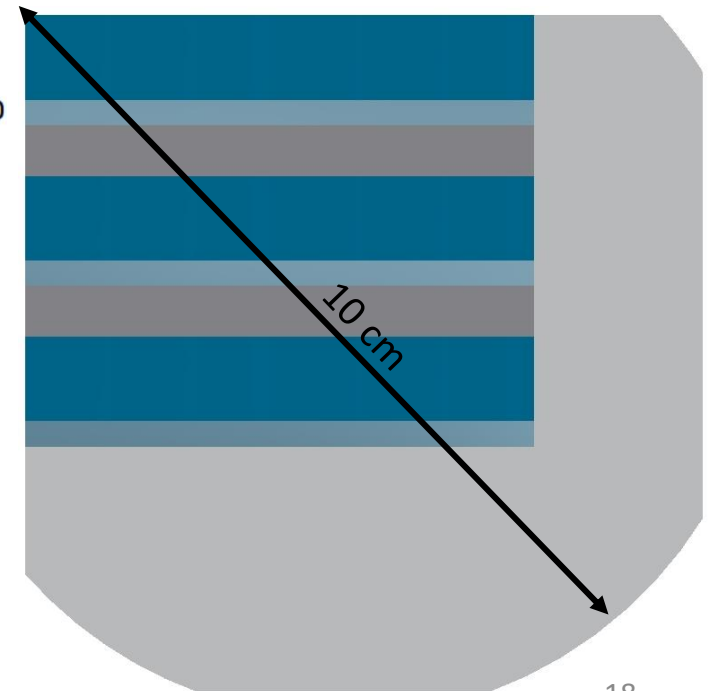


Support materials

Support materials considered



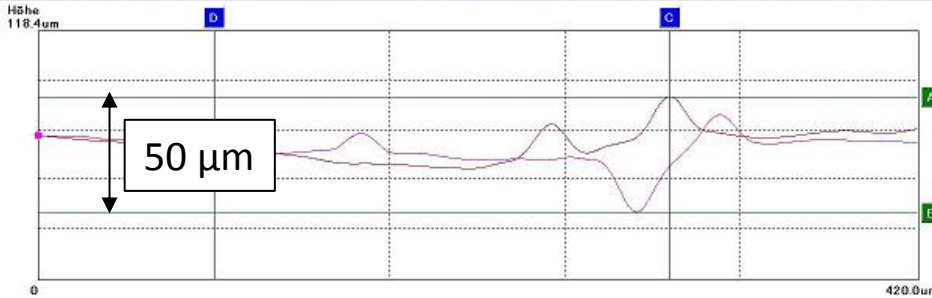
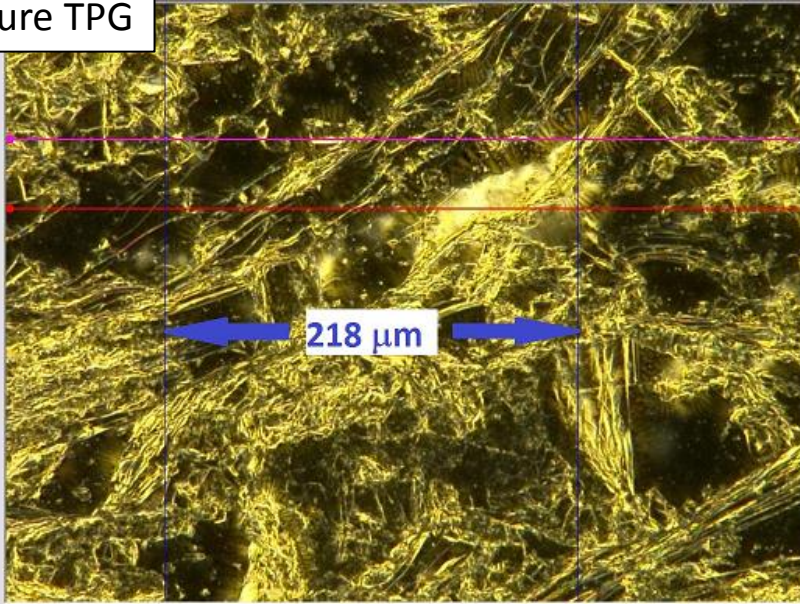
...but not larger than 8 cm diameter



Support materials considered

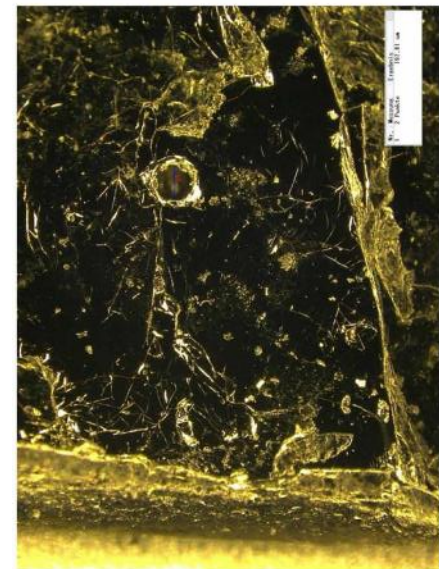
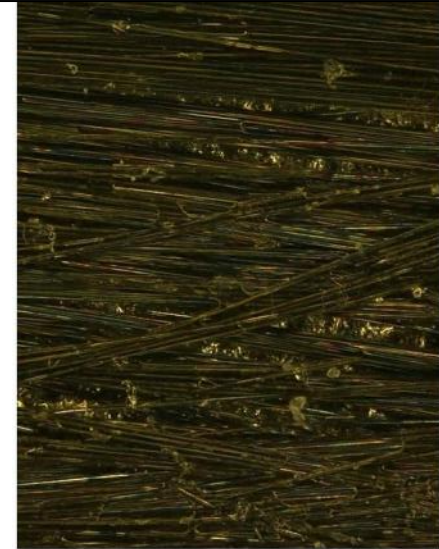


Pure TPG



v.s.

Reinforced TPG -> CF-TPG-CF

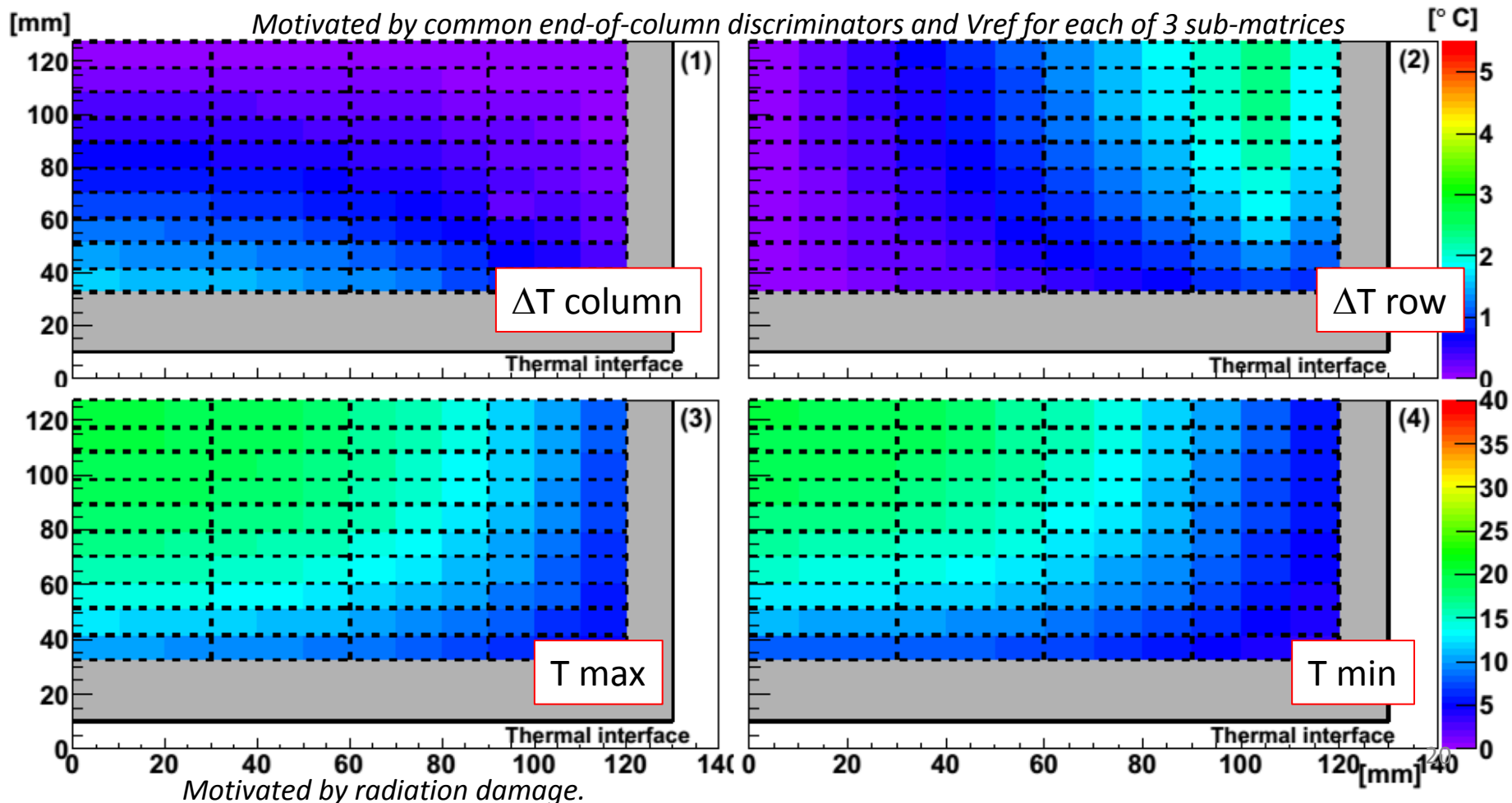


What can we gain from CF-TPG-CF sandwich developed by for the CMS upgrade ?

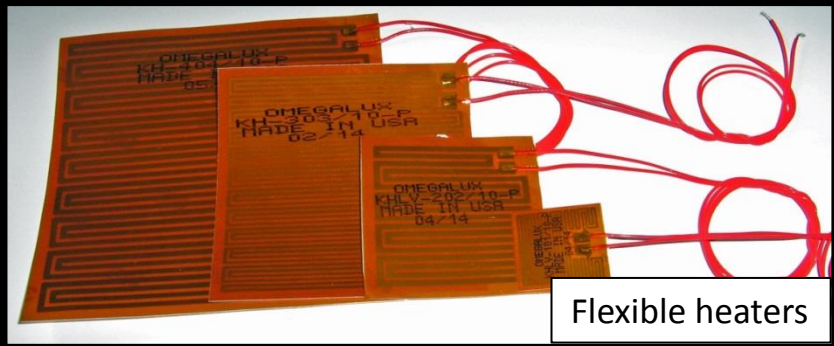
Thermal simulations



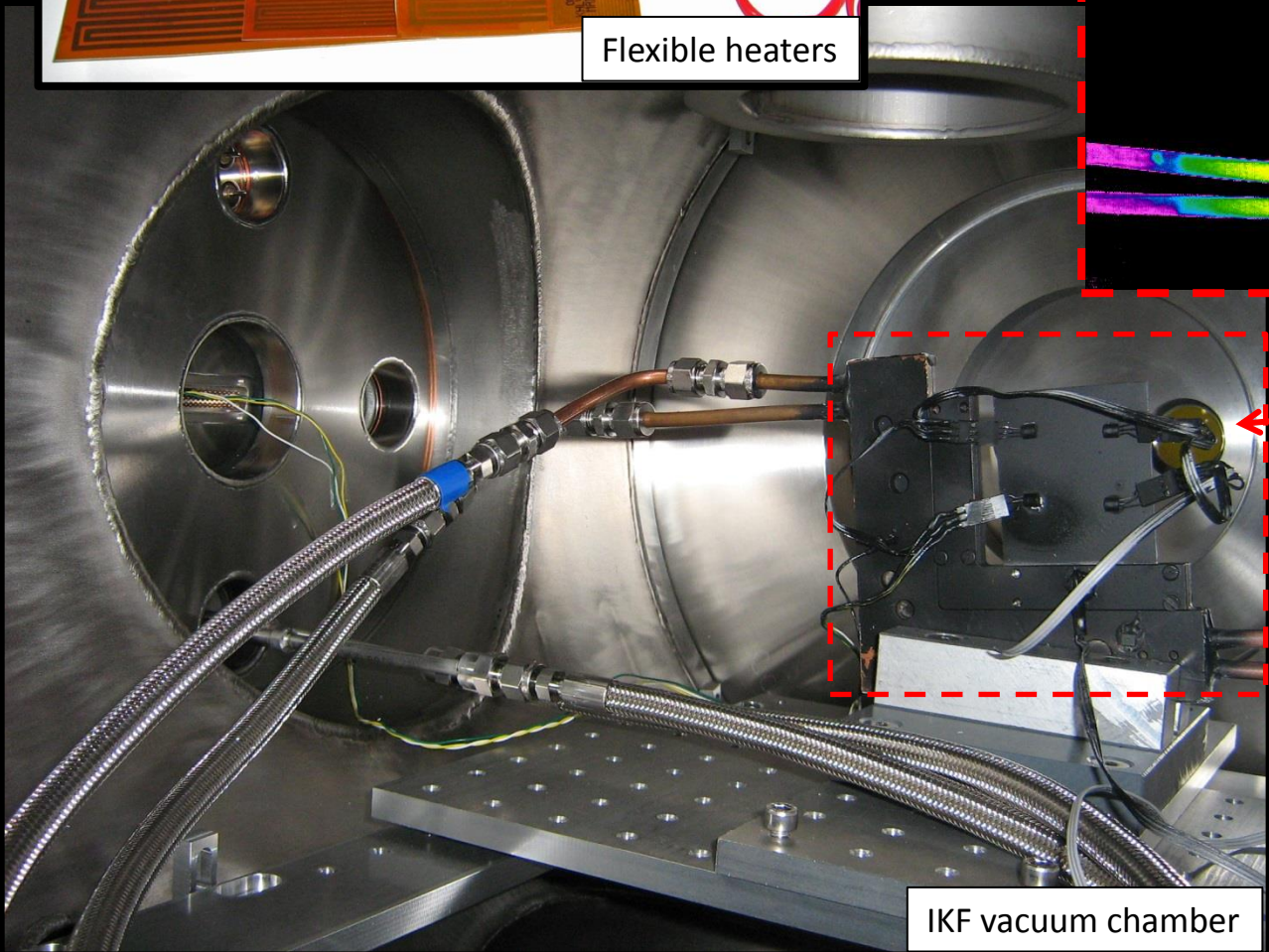
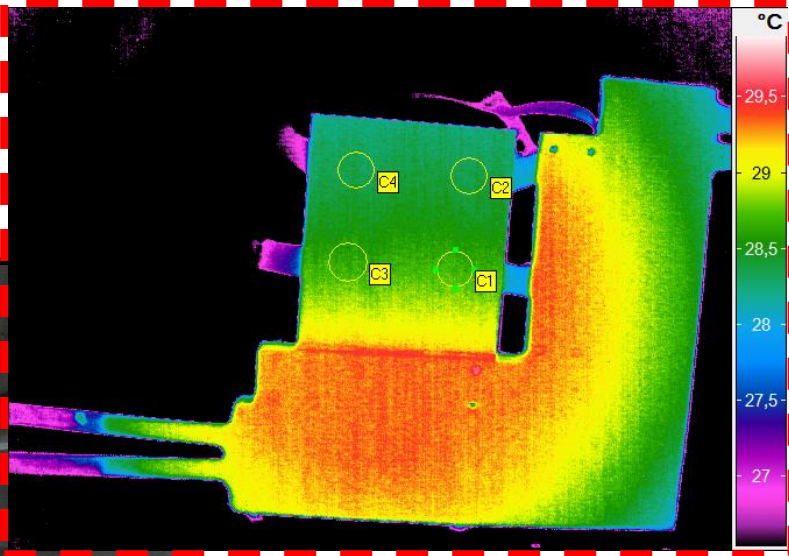
- Station 3
- Pure TPG 380 μm
- Expected power consumption of about 185 mW/cm^2
- $T_{\text{interface}} = -20^\circ\text{C}$



Validation of thermal simulations



Flexible heaters



IKF vacuum chamber

IR view-port

- Temperature range of $-20^{\circ}\text{C} \pm 10^{\circ}\text{C}$
- Power consumption up to $300 \text{ mW}/\text{cm}^2$

So far :
Swagelok + silicone oil
-> ...is leaking

Open issues



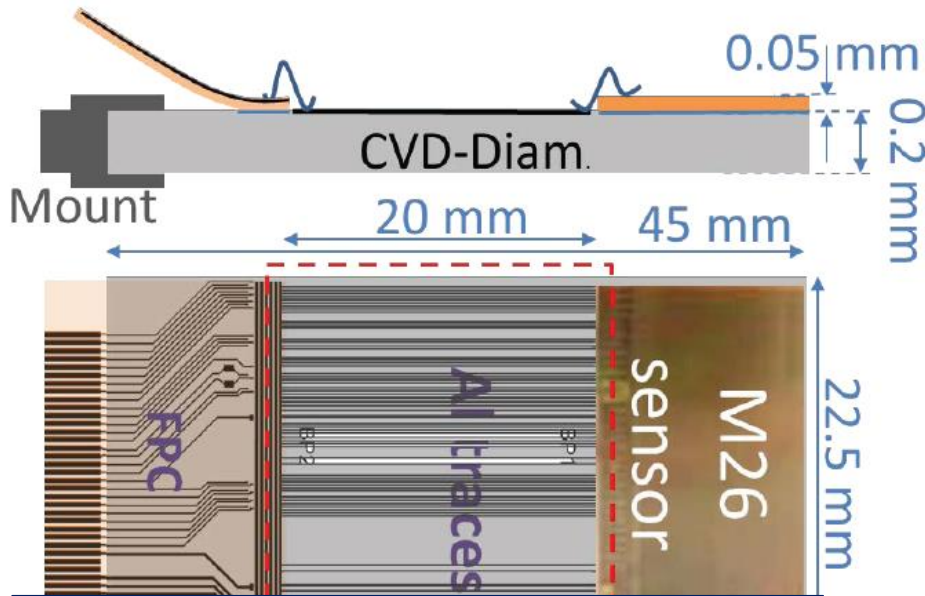
- CVD diamond size – max diameter of CVD wafer 8 cm so far (we try 10 cm with DiamondMaterials but risky)
 - ElementSix offers 10 cm CVD but 500 μm thick
- CF-TPG-CF or TPG ? Pure TPG for station 1-3 ordered from
- High-density vacuum feed-throughs (differential signals & power)
- Movement inside vacuum and magnetic field
- Al based FPCs
- Metrology – ALICE/ATLAS/CMS ? Is CERN opened for external/CERN recognized experiments ?



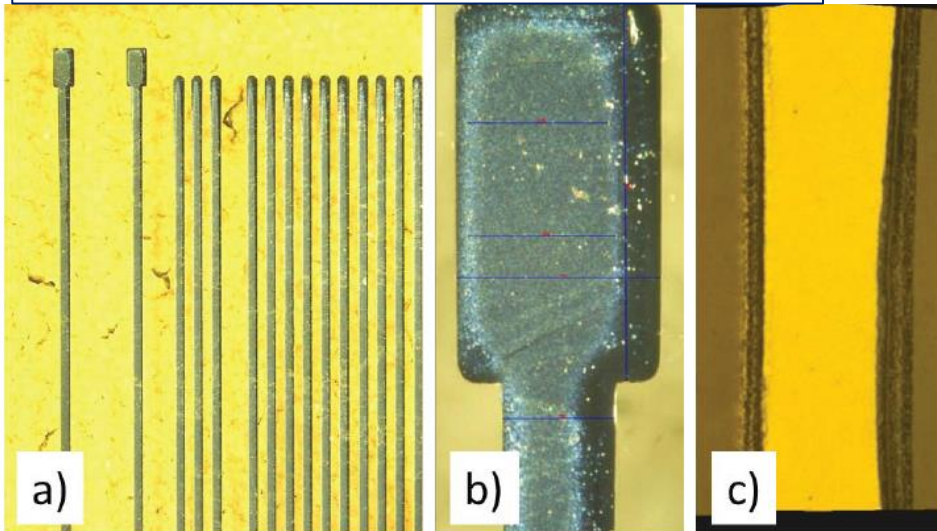
That's all Folks!

Thank you for your attention...

?????



Together with Hochschule RheinMain and GSI



Cables are material budget... -> Try to avoid cables ?

Idea: Put Al traces directly on the CVD diamond carrier required for cooling and mechanical support.

Results:

- Thickness: 2 (2.8) mm , feature sizes: 50...100 mm
- Litho: Chemical wet etching, lift-off
- Interim results:
 - Pull tests: **sufficient adhesion** of Al-traces
 - Electrical characterization (4-terminal sensing, wire bonding): Al thickness homogeneity depends on the technique applied (best: lift-off), **specific resistance of Al-traces can be factors (x3) higher compared to bulk aluminum**, to be adjusted by sputtering process. Relevant regarding layout of traces!
- Next steps:
 - **Improve uniformity and thickness** (up to 5 μm) of Al traces
 - **Decrease the specific resistance**
 - Demonstrate M26 r/o